

n-漂移层  
n-type (N-doped  $2 \times 10^{14}$   
 $\text{cm}^{-3}$ ,  $3\mu\text{m}$ )

n+型 SiC 4H衬底

步骤1: 基础外延结构

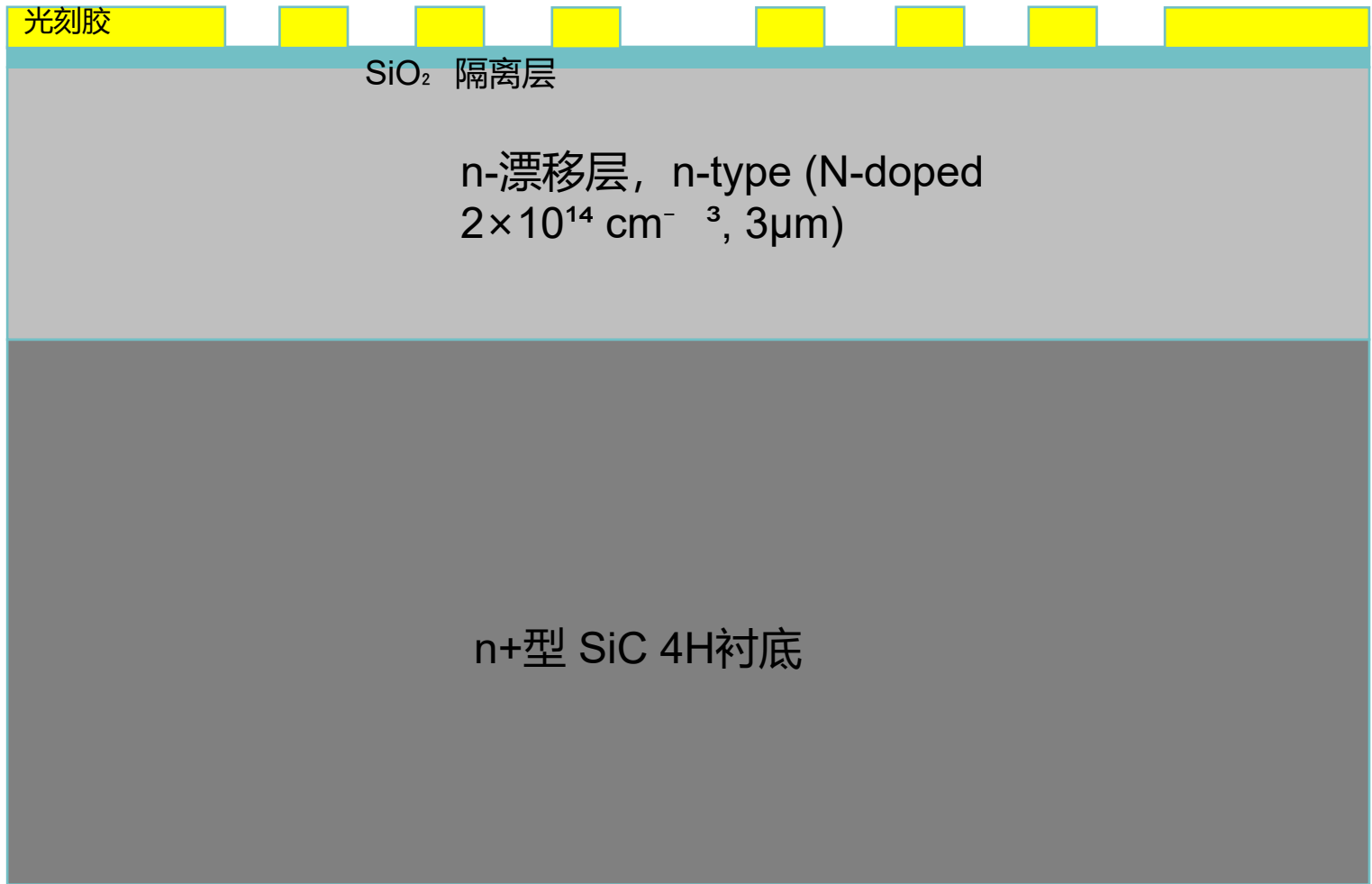
SiO<sub>2</sub> 隔离层 (热氧化生长)

n-漂移层

n-type (N-doped  $2 \times 10^{14}$   
 $\text{cm}^{-3}$ ,  $3\mu\text{m}$ )

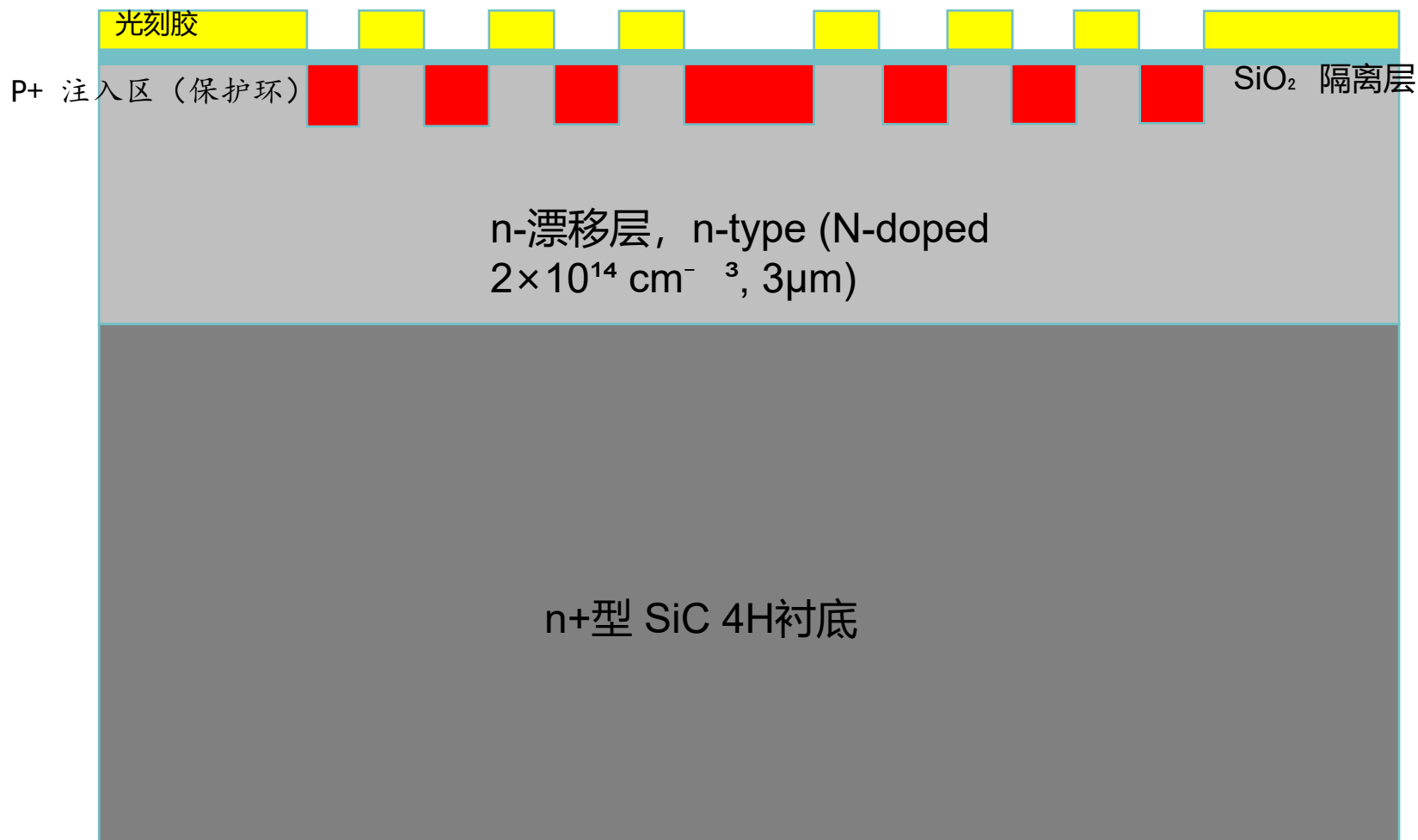
n+型 SiC 4H衬底

步骤2: 热氧化SiO<sub>2</sub>



未覆盖光刻胶区域的SiO<sub>2</sub>被刻蚀去除, 露出漂移层表面用于后续注入

步骤3: 光刻刻蚀掩膜



步骤4: 离子注入 P+

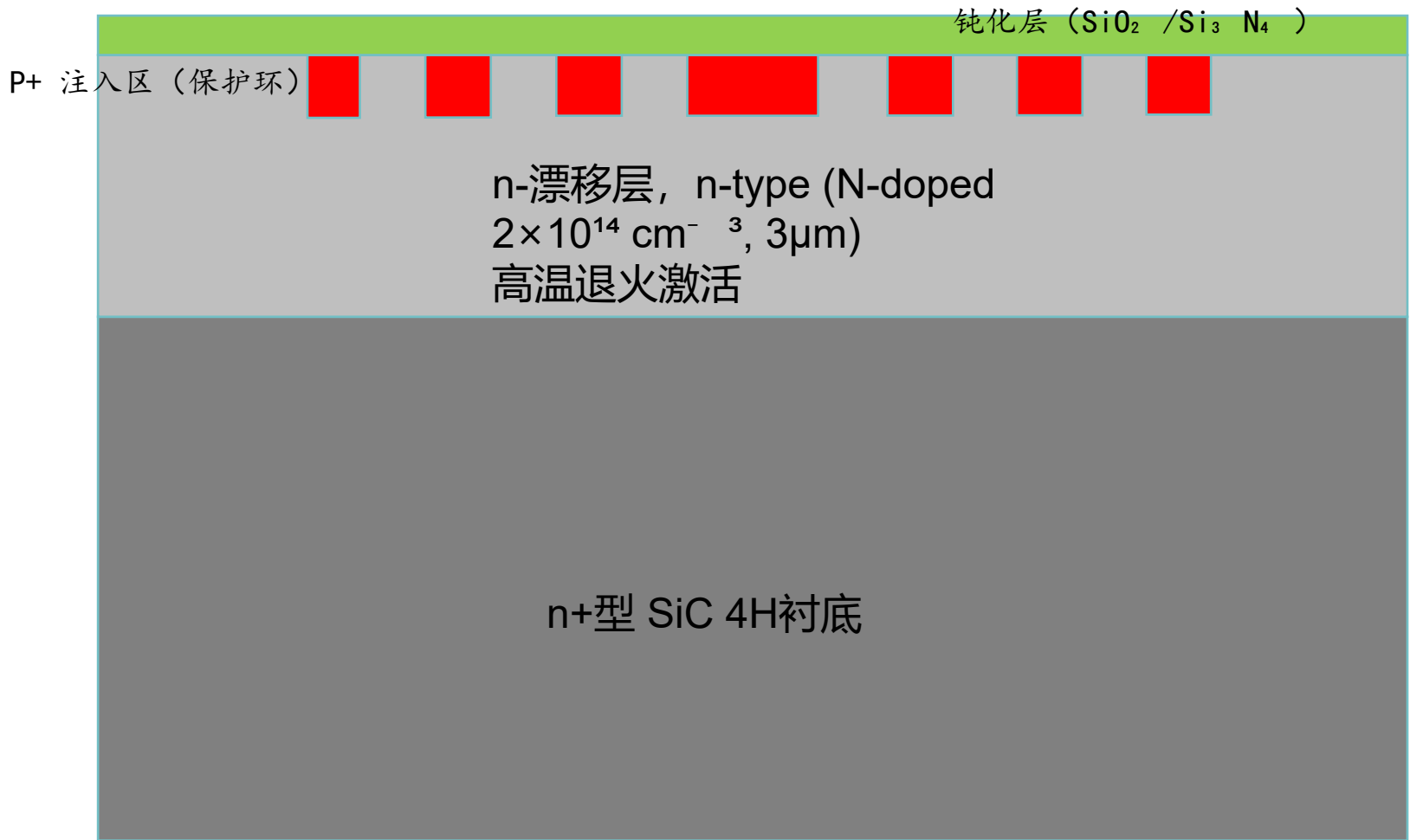
P+ 注入区 (保护环)



n-漂移层, n-type (N-doped  
 $2 \times 10^{14} \text{ cm}^{-3}$ ,  $3 \mu\text{m}$ )  
高温退火激活

n+型 SiC 4H衬底

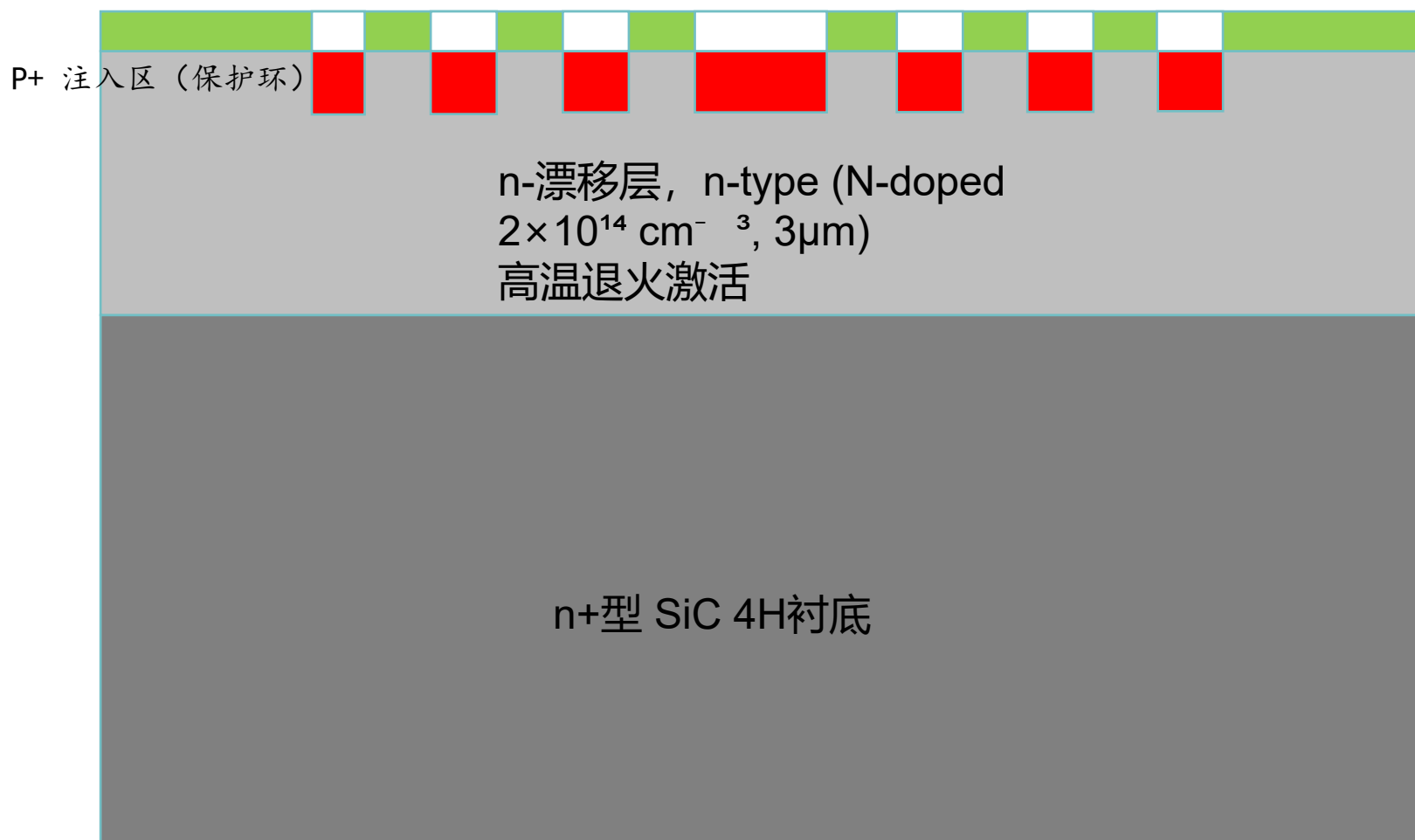
步骤5: 去掩膜高温退火



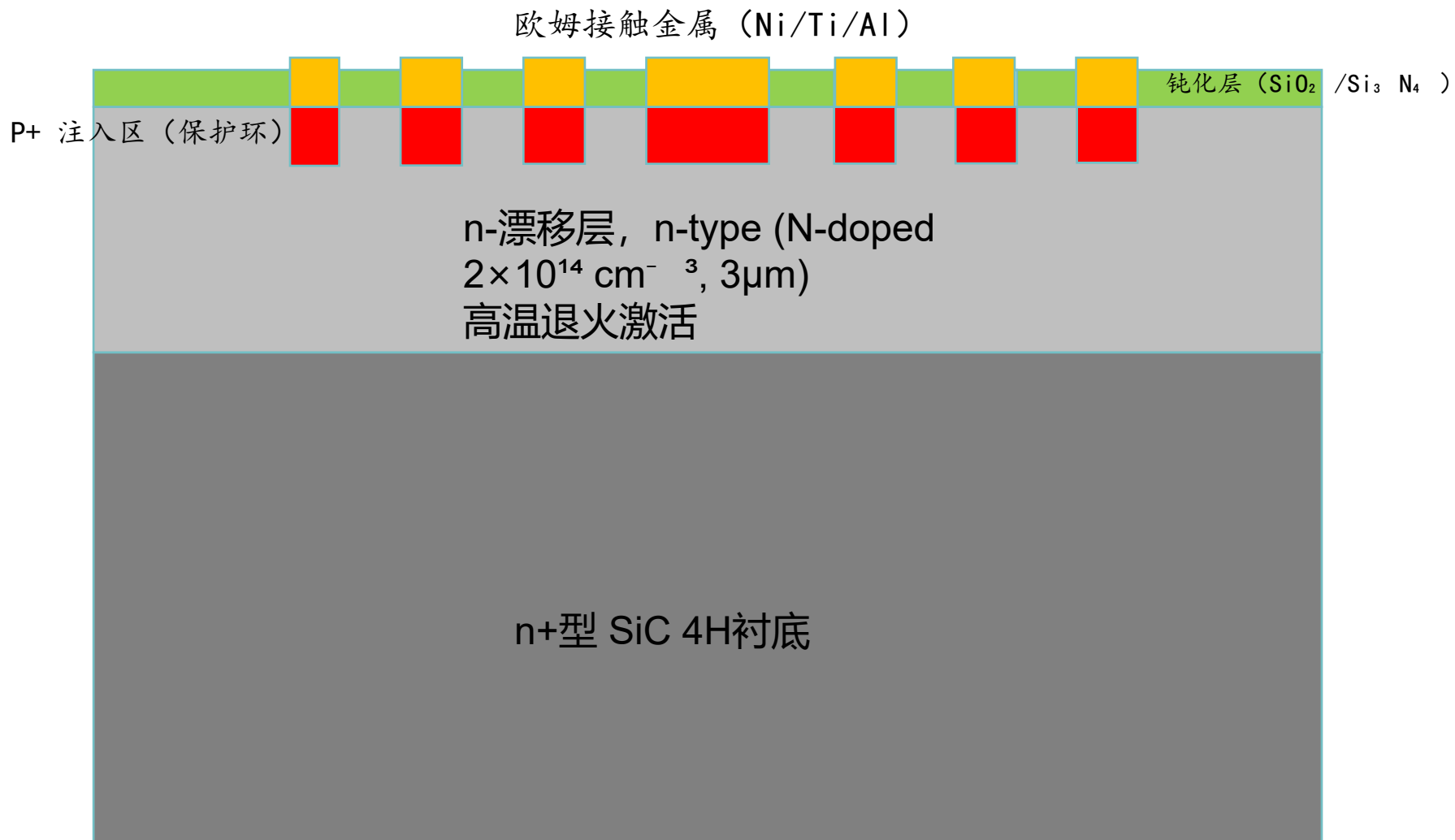
步骤6: 生长钝化层

刻蚀开窗 (接触孔)

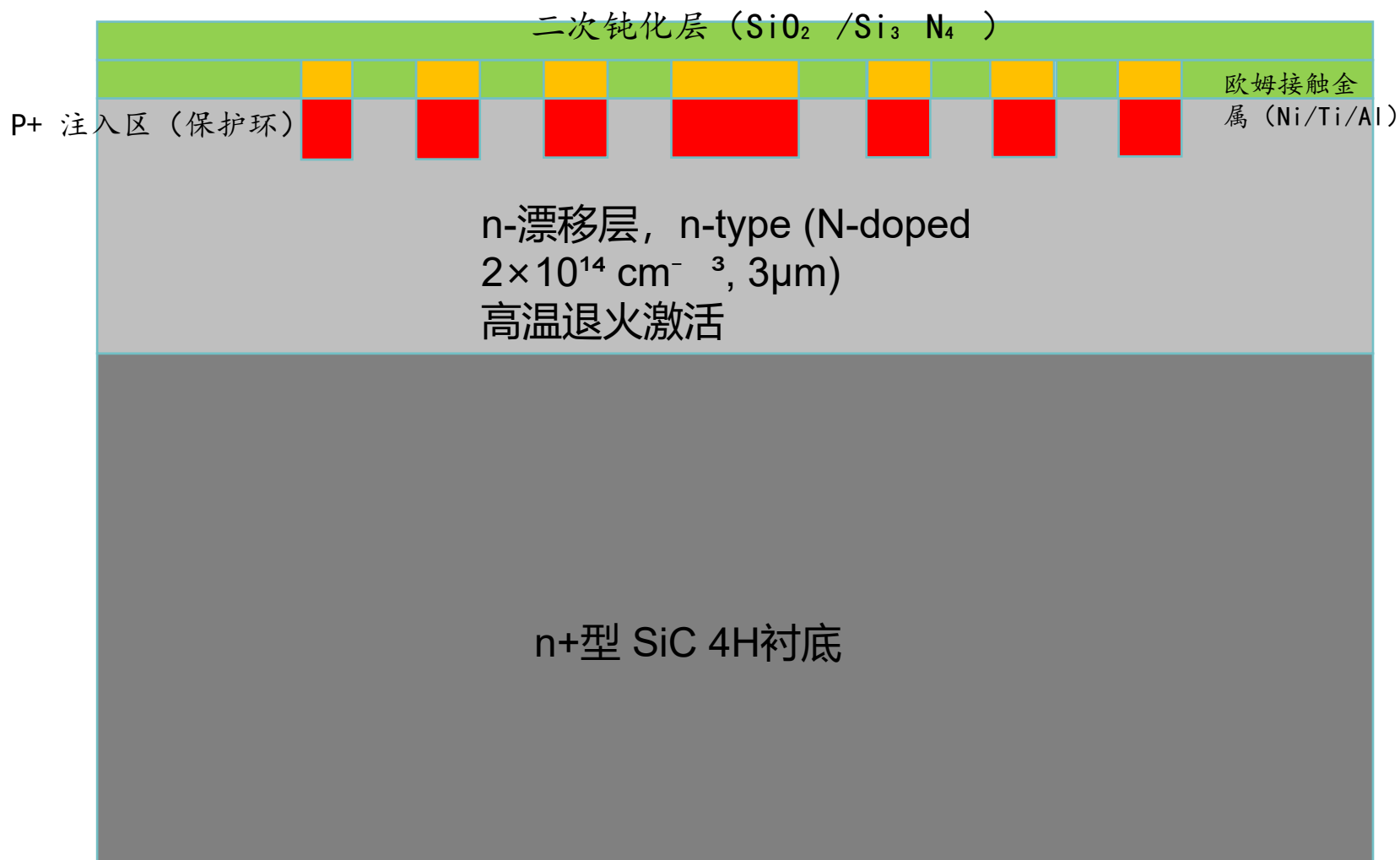
钝化层 ( $\text{SiO}_2$  /  $\text{Si}_3\text{N}_4$ )



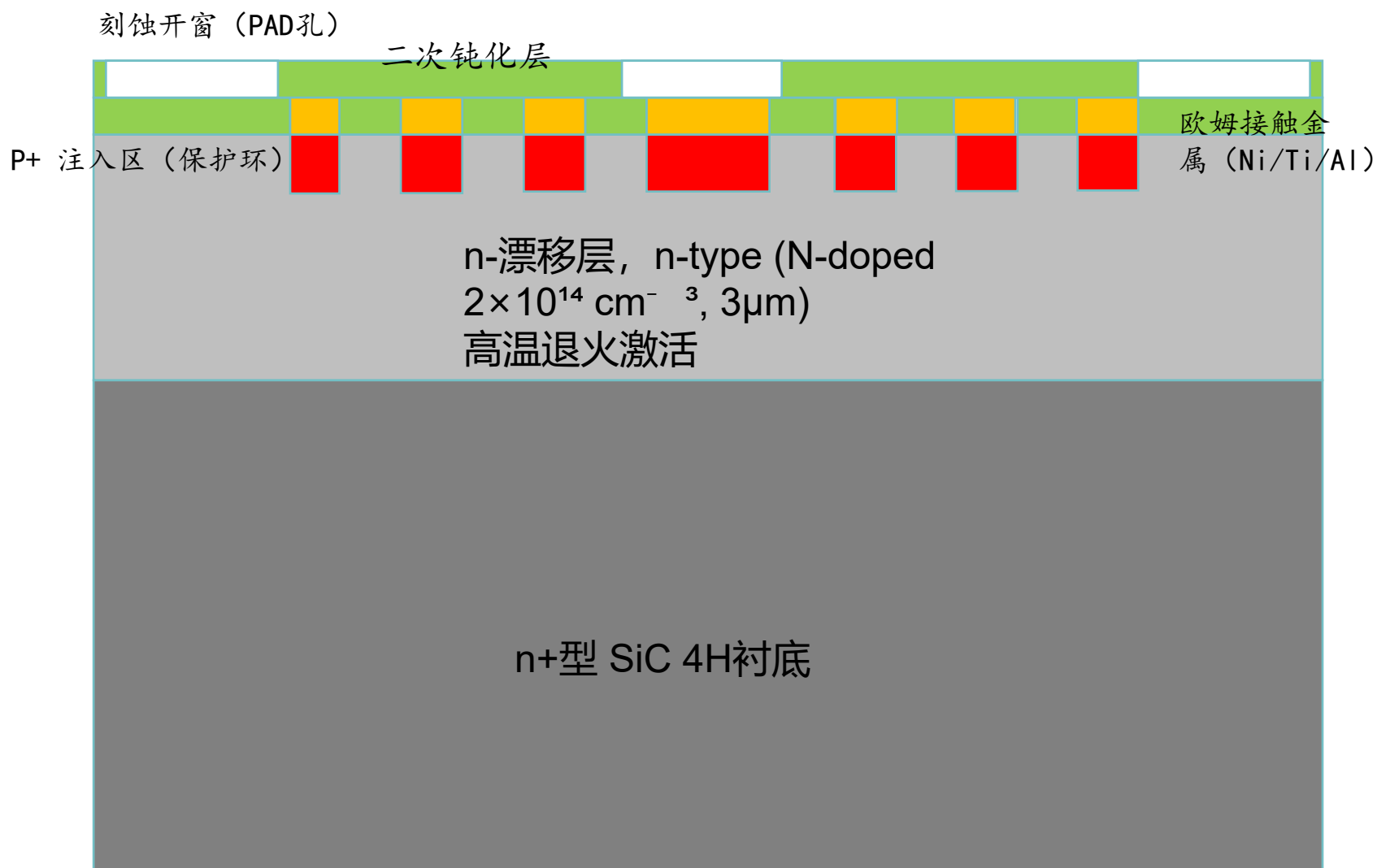
步骤7: 刻蚀钝化层



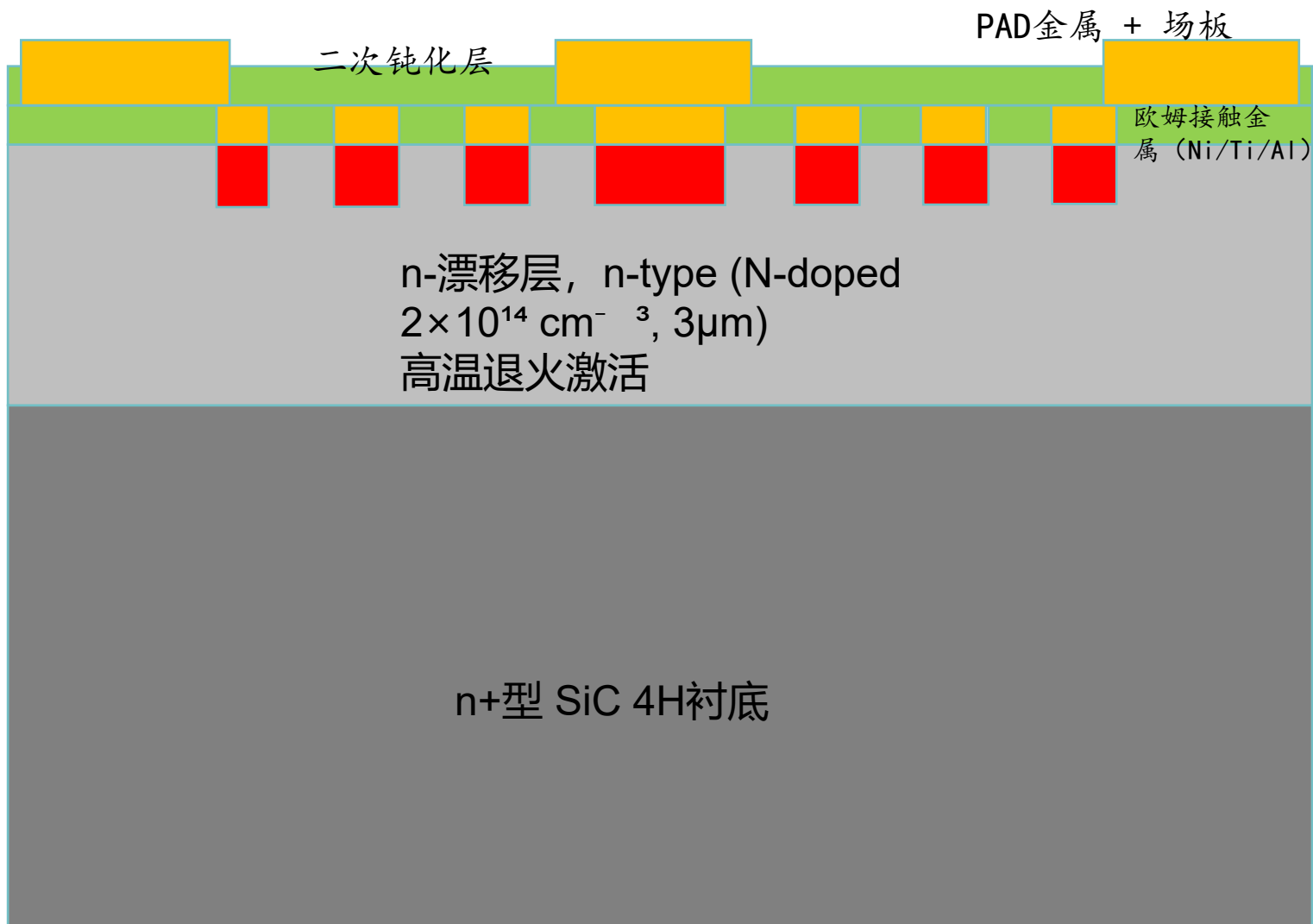
步骤8: 溅射欧姆接触金属  
(Ni/Ti/Al)



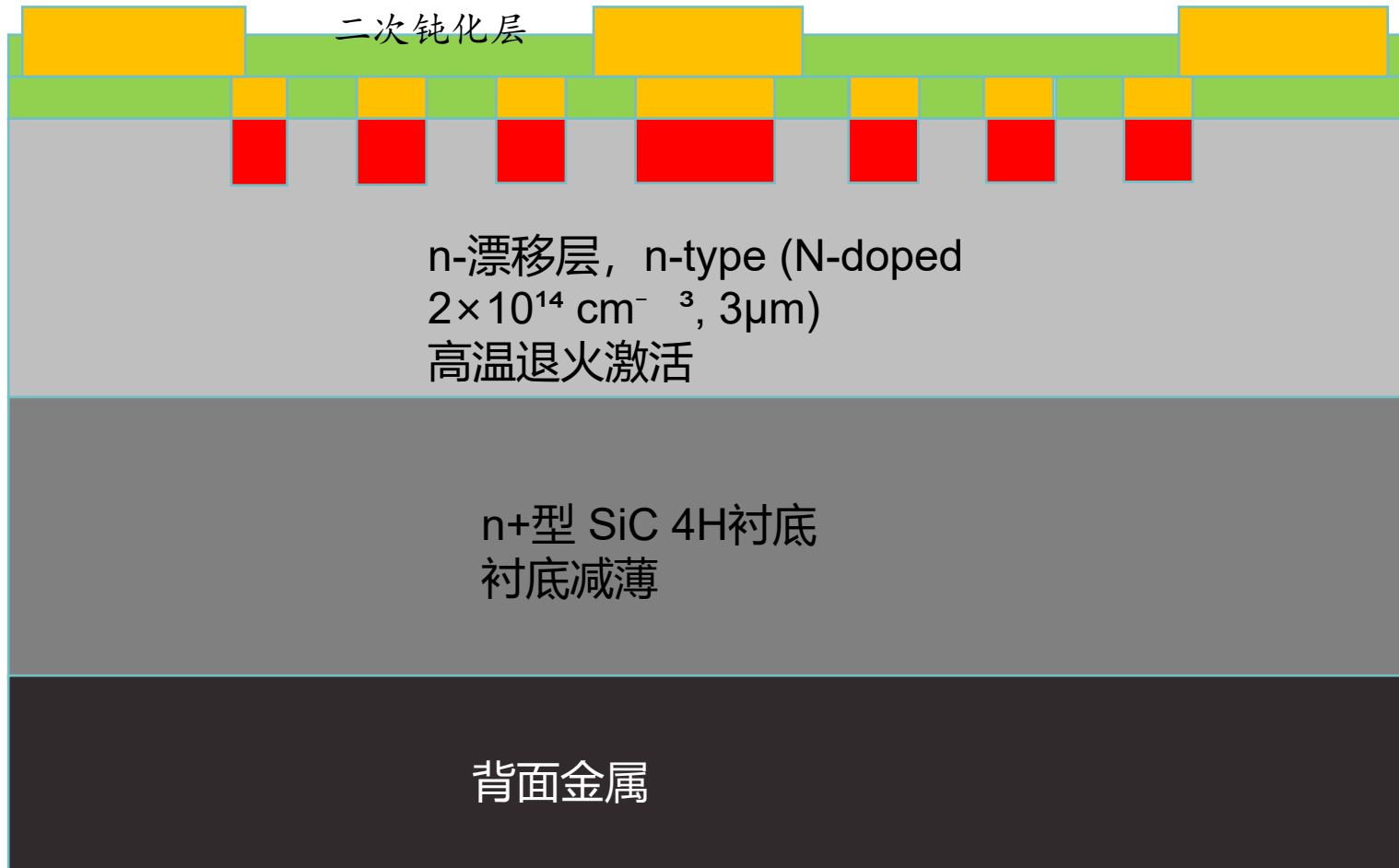
步骤9: 沉淀钝化层



步骤10: 刻蚀钝化层



步骤11: 沉淀PAD金属 + 场板



步骤12: 衬底减薄 + 背底金属沉淀

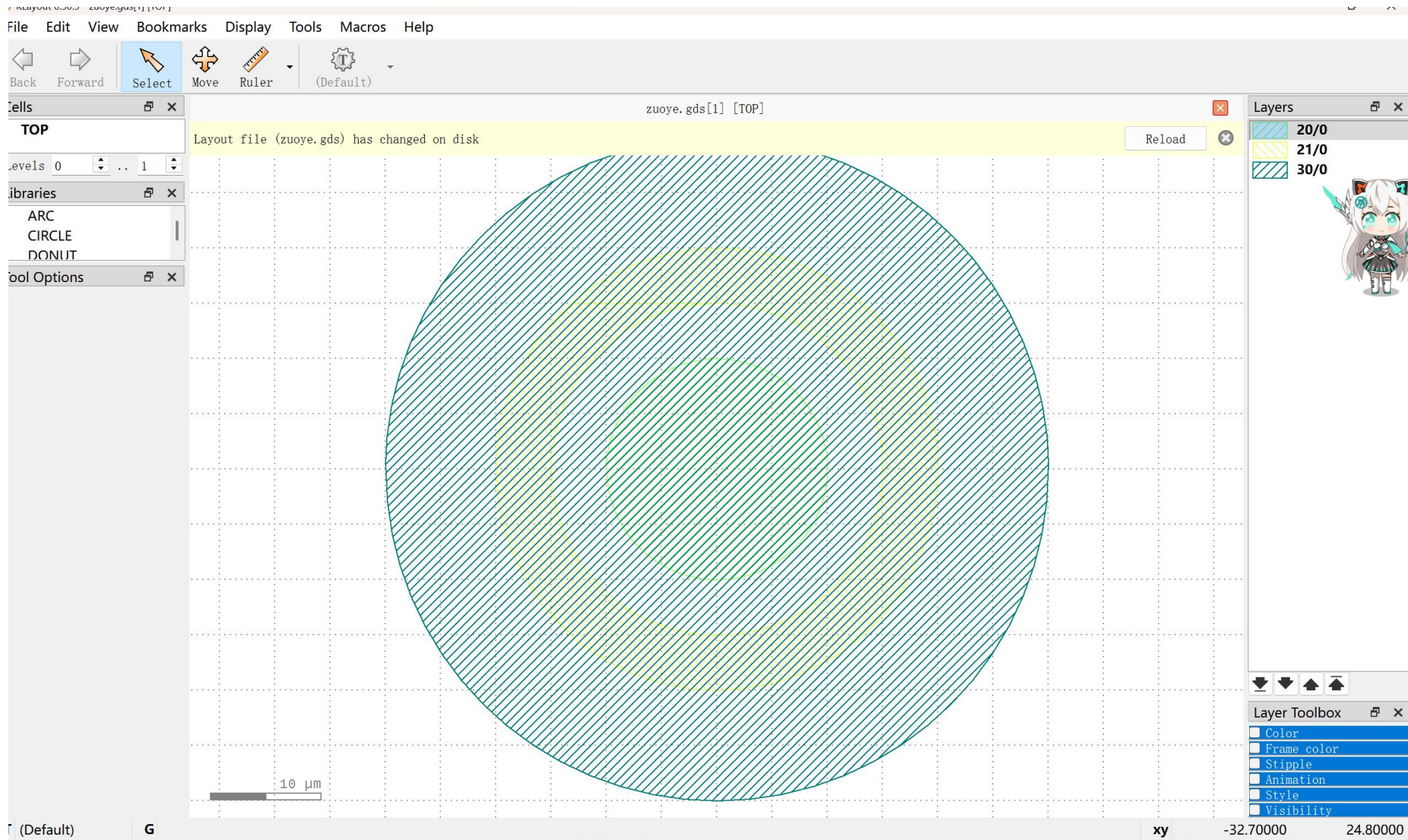
The image shows a Python IDE window with a file named 'zuoye.py' open. The code in the editor is as follows:

```
1 import pya
2 import math
3
4 layout = pya.Layout()
5 top = layout.create_cell("TOP")
6
7 l_anode = layout.layer(20, 0)
8 l_guard = layout.layer(21, 0)
9 l_border = layout.layer(30, 0)
10
11 cx = 0
12 cy = 0
13
14 r_anode = 10000
15 r_guard_outer = 20000
16 r_guard_inner = 15000
17 r_border = 30000
18
19 def make_circle(x0, y0, r):
20     pts = []
21     for i in range(0, 65):
22         angle = 2 * math.pi * i / 64
23         x = x0 + r * math.cos(angle)
24         y = y0 + r * math.sin(angle)
25         pts.append(pya.Point(int(x), int(y)))
26     return pya.Polygon(pts)
27
28 anode = make_circle(cx, cy, r_anode)
29 top.shapes(l_anode).insert(anode)
30
31 guard_outer = make_circle(cx, cy, r_guard_outer)
32 guard_inner = make_circle(cx, cy, r_guard_inner)
33 guard = pya.Region(guard_outer) - pya.Region(guard_inner)
```

The console at the bottom shows the command to run the macro:

```
Running macro C:/Users/31646/KLayout/pymacros\zuoye.py
Done
```

klayout代码



中间那个绿色圆，代表阳极区（有源区）。  
外面套着的黄绿色圆环，代表保护环（终端刻蚀区）。  
整个图最外面那个深绿色大圆，代表边界区（划片槽边界）。